

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Renken et al.		
Title:	Process Condition Sensing Wafer and Data Analysis System		
Application No.:	10/685,550	Filing Date:	October 14, 2003
Examiner:	Samir M. Shah	Group Art Unit:	2856
Docket No.:	SENS.005US1	Conf. No.:	4924

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION AND AMENDMENT

Sir:

This is in response to the final Office Action dated March 29, 2007.

Claim Amendments are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 8 of this paper.

Reconsideration is kindly requested in light of the following amendments and remarks.